

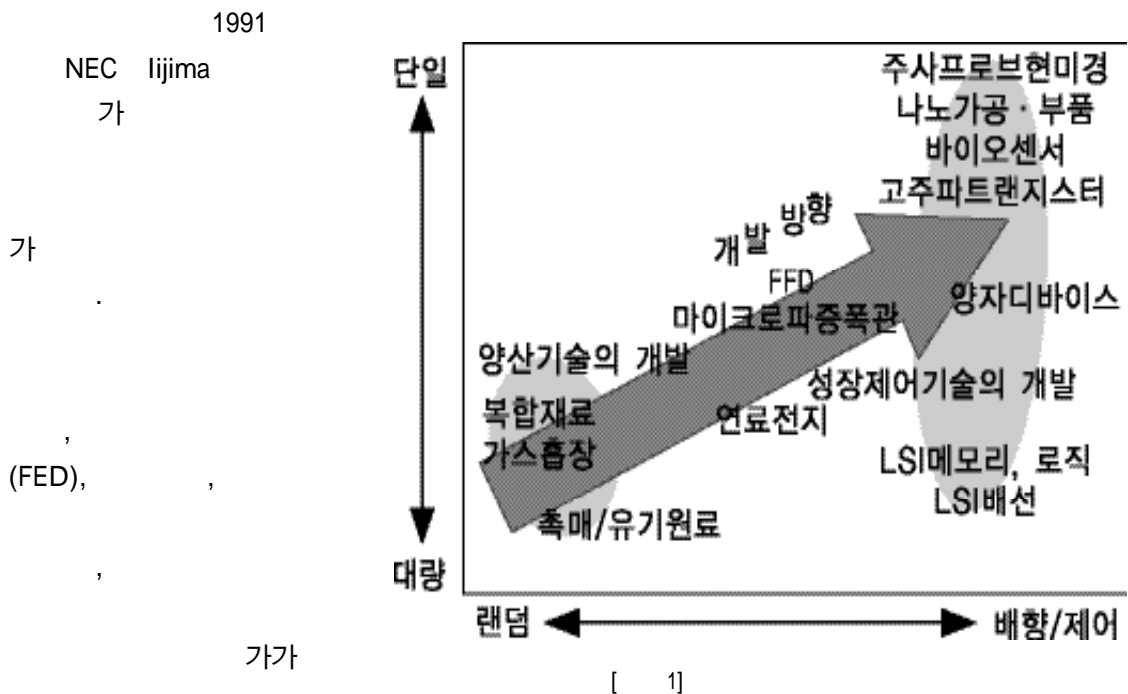


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 (Chemical Vapor Deposition; CVD)  
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CNT	CNT	SWCNT/DWCNT MWCNT
		(Arc Discharge) Laser Ablation/Laser Vaporization CVD(Plasma/Thermal) (Electrolysis) (Flame Synthesis) HipCo (Liquid Phase)
		SWNT/MWNT /
	CNT	CNT
CNT	Device	Device FED(Field Emission display) X-ray Generation LCD Backlight Lamp FESEM
	Nano Electronics	Nano Electronics FET(Field Emission Transistor) Sensor Wire/Interconnector Memory Logic Energy
	Energy	Gas ( , , ) Capacitor
	Mechatronics	Mechatronics Nano Probe (AFM/SPM Tip) Nano Tweezer Nano Pipet/Nano Pipe (Nanocapsule, Nanowhiskers) Nano Composite
	Nano composite	EMI Shield EMI Absorber Electrostatic Dissipation(ESD)

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1) 工業材料2003 1 pp.51-55